Working toward XHV

Characterization and Improvements of the Vacuum System for a GaAs Photoemission Electron Source

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- 6 (12) GeV Electron accelerator for Nuclear Physics
- 85% polarization, up to ~200 μA beam to three experimental halls
- DC photoemission electron source
- Lifetime depends largely on vacuum
- Future accelerators (CLIC, EIC, ILC)

higher current required







Polarized Electron Source

- DC photoemission source
- Polished electrodes

4 pairs

- 100-130 kV
- Strained superlattice GaAs/GaAsP photocathode





Strained superlattice GaAs/GaAsP Bandwidth semiconductor QE ~ 1%, Pol ~ 85%

100 nm

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Vacuum affects cathode lifetime

Poor Vacuum, lower photocathode lifetime (red) Better vacuum,

higher lifetimes

Other lifetime factors 🎽

- photocathode properties
- field emission
- beam handling







How to reach XHV \equiv P < 0.76x10⁻¹² Torr?







Less gas in: reduce outgassing







Less gas in: reduce outgassing

- Outgassing measured by Spinning Rotor Gauge rate of rise
- Semi-vacuum bake
 - Hot air outside
 - Vacuum inside



Time (hours)

chamber	treatment	Q (Torr·L/s·cm ²)
304	900°C 2 hours before welding	9 x 10 ⁻¹³
93 liter, 316LN EP	400°C, ~10 days	1.5x10 ⁻¹³
38 liter, 316, thin wall, EP	400°C, ~10days	1.13x10 ⁻¹³
12 liter, 304	400°C, ~10 days	3.5x10 ⁻¹⁴ ?





More gas out: improve pumping

- Pump system combines
 - non-evaporable getters (NEG)
 - ion pumps
- Rotate NEG modules to eliminate line of sight from walls to cathode/anode gap
- Add ~400°C activation during 250°C bake







Pumping



• P_{calc}=QA/S

- Approaching calculated pressures
- Heat treated chambers: closer to expected pressure
- All pressures
 nitrogen equivalent

Pressure still not as low as predicted





Do ion pumps limit a chamber's ultimate pressure?

System 1: 40 L/s ion pump (diode)

Flapper Valve	HV Chamber IP	Extractor Gauge	
Open	0.1 nA	8.8x10 ⁻¹² Torr	
Closed	3.5 nA	8.2x10 ⁻¹² Torr	Hurts

Flapper valve between ion pump and NEG pumped chamber with extractor gauge

System 2: old custom diode PE ion pump

Flapper Valve	HV Chamber IP	Extractor Gauge
Open	0.5 nA	7.0x10 ⁻¹² Torr
Closed	1.8 nA	7.8x10 ⁻¹² Torr
Open	0.3 nA	7.6x10 ⁻¹² Torr
Closed	1.1 nA	8.8x10 ⁻¹² Torr

need more data

trying XHV option on Gamma ion pumps, no clear results yet Reduce SIP size?





UHV ion pump supplies

• UHV ion pump power supplies



- power ion pumps once turned on
- monitor current down to <1 nA
- sensitive relative pressure monitor
 - diagnose vacuum activity due to field emission without glowing filament
- Work in progress to extend lower measurement limit
- Now can read 10 picoA, see vacuum activity at that level





Measure pressure

- 2x10⁻¹² Torr limit
 Real pressure?
 Gauge limitation?
- Oerlikon Leybold extractor gauges
 - x-ray limit quoted
 <0.76x10⁻¹² Torr
 - recessed collector
 - vary reflector voltagex-ray limit measurement







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Measure X-ray limit



method published by Fumio Watanabe, J. Vac. Sci. Technol. A **9**, 2744 (1991)

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Measure X-ray limit



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Better background subtraction

Measure "emission off" background with gauge elements biased





Reflector voltage (V)

First extractor: biased, no emission current/pressure measured

Second extractor: biased, emission on no current/pressure measured x-ray limit near 2x10⁻¹² Torr as installed?





X-ray limit subtraction





Watanabe BBB Gauge



Fumio Watanabe JVSTA 28(3) p.486 2010



Deflector variation background below IE540 detection limits (use electrometer below 1x10⁻¹³ Torr)

230° deflector, BeCu housing pressure measurement limit quoted $4x10^{-14}$ Torr !!! Leybold IM540 controller + bias







Gauge comparison system

- Old gun chamber
- NEG module array
- 25 L/s SEM/XHV ion pump
- 2 extractor gauges
- 1 BBB gauge
- 1 device formerly known as RGA
- Spinning rotor gauge
- Two gas inlet manifold with leak valves
- Outgassing sub-optimal
- Pumps not optimally activated
- No gauges with traceable or up-to-date calibration







First data: Gauge comparison





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- Extractor and BBB recorded with hydrogen gas introduction
- Extractor readings slightly higher
 - calibration issue
- % difference increases at lower pressures need more data
- Need data below 5x10⁻¹² Torr
 - Better test chamber



Spinning Rotor Gauge Comparison



Threefold work toward XHV

- Outgassing measurably reduced
 - 400°C long heat treatment
 - Reduced area of thick flanges
- Pumping configuration improved
 - Rotated GP1250 NEG modules
 - Activate during bakeout
 - Still investigating ion pump behavior
- Accurate pressure measurement
 - Extractor gauge "as installed" x-ray limit measurements
 - New Watanabe BBB gauge first data

Thank you for your attention





Installed Load-Locked gun





